Special Issue

Image Processing: Technologies, Methods, Apparatus

Message from the Guest Editors

Image processing is at the forefront of technological research, with significant breakthroughs. Within this background, this Special Issue aims to provide a concise collection of studies dealing with image processing and provide important information to scientists and stakeholders for the development of technologies and systems based on sensors. Articles and review articles may address, but are not limited to, the following topics:

- Novel algorithms for image enhancement, segmentation, and recognition;
- Machine learning and AI applications in image processing;
- Computational imaging techniques;
- Hardware and software innovations for image acquisition and analysis;
- Biomedical, industrial, and security applications of image processing;
- High-rate detector and an event detector.

Guest Editors

Dr. Benjamin Milgrom

Prof. Dr. Andrei Doncescu

Prof. Dr. Cheonshik Kim

Prof. Dr. Ki-Hyun Jung

Deadline for manuscript submissions

closed (20 May 2026)

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Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal *Applied Sciences* has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

Editor-in-Chief

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